

DO NOT ENTER: /SM/
02/16/2010

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: 1792

Serial No.: 10/528,137

Examiner: **MACARTHUR, Sylvia**

Filed: **December 12, 2005**

P.T.O. Confirmation No.: 2307

**FOR: SUBSTRATE PROCESSING APPARATUS AND METHOD FOR
MANUFACTURING A SEMICONDUCTOR DEVICE**

RESPONSE UNDER 37 CFR §1.116
- EXPEDITED RESPONSE -
GROUP ART UNIT 1792

*Entered with RCE 3/9/10
mw 3/10/10*

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

February 4, 2010

Sir:

In response to the Final Office Action dated **November 13, 2009**, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 12 of this paper.